

<b>FORM PTO-1449</b> (Rev. 2-32)	<b>U.S. Department of Commerce</b> <b>Patent and Trademark Office</b>	<b>Atty. Docket No.</b> 03-06	<b>Serial No.</b>
		<b>Applicant:</b> Harry Levinson and Thomas White	
		<b>Filing Date:</b> January 12, 2004	<b>Group:</b>

**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**  
 (Use several sheets if necessary)

## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc).

			A. Mikkelsen et al., <i>EUVL Mask Flatness and Electrostatic Chucking Analysis</i> , Presented at the 47 <sup>th</sup> International Conference on Electron, Ion and Photon Beam Technology and Nanofabrication (Tampa, FL) and submitted to the <i>Journal of Vacuum Science and Technology B</i> , Nov/Dec, 2003

<b>EXAMINER</b> Danny Nguyen	<b>DATE CONSIDERED</b> 8/7/06
---------------------------------	----------------------------------

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication.